

Appln. No. 10/621,497  
Response dated February 15, 2006  
Reply to Office Action dated December 7, 2005

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2006  
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RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 1765

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Tetsuhiro Iwai, et al.  
Appln. No. : 10/621,497  
Filed : July 17, 2003  
Title : PLASMA PROCESSING APPARATUS AND PLASMA  
PROCESSING METHOD

Conf. No. : 2610  
TC/A.U. : 1765  
Examiner : Lan Vinh

Customer No. : 000,116  
Docket No. : 35908

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE "C"**  
**AFTER FINAL UNDER RULE 1.116**

Sir:

This communication is filed in response to the Office Action dated December 7, 2005 (Paper No. 120105). The three-month period for responding to the Office Action expires on March 7, 2006.

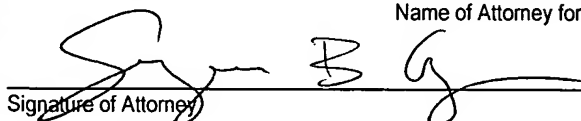
The following remarks are made for the Examiner's consideration.

**Remarks/Arguments** begin on page 2 of this paper.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below.

**Suzanne B. Gagnon**

Name of Attorney for Applicant(s)

  
Signature of Attorney

**February 15, 2006**

Date